

PATENT ASSIGNMENT COVER SHEET

Electronic Version v1.1
 Stylesheet Version v1.2

EPAS ID: PAT5274802

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|---|---|
| SUBMISSION TYPE: | NEW ASSIGNMENT |
| NATURE OF CONVEYANCE: | ASSIGNMENT |
| CONVEYING PARTY DATA | |
| Name | Execution Date |
| LIN-CHEN HO | 06/28/2016 |
| WEI-WEN TSAI | 06/28/2016 |
| CHENG-PING LEE | 06/28/2016 |
| JIUN-FANG WANG | 06/28/2016 |
| RECEIVING PARTY DATA | |
| Name: | Rohm and Haas Electronic Materials CMP Holdings, Inc. |
| Street Address: | 451 Bellevue Road |
| City: | Newark |
| State/Country: | DELAWARE |
| Postal Code: | 19713 |
| PROPERTY NUMBERS Total: 1 | |
| Property Type | Number |
| Application Number: | 16080489 |
| CORRESPONDENCE DATA | |
| Fax Number: | (302)283-2144 |
| <i>Correspondence will be sent to the e-mail address first; if that is unsuccessful, it will be sent using a fax number, if provided; if that is unsuccessful, it will be sent via US Mail.</i> | |
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| Correspondent Name: | PATRICIA CONNELL |
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| ATTORNEY DOCKET NUMBER: | 78879 |
| NAME OF SUBMITTER: | PATRICIA A. CONNELL |
| SIGNATURE: | /Patricia A. Connell/ |
| DATE SIGNED: | 12/10/2018 |
| Total Attachments: 2 | |
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| source=78879PCTAssignmetExecuted#page2.tif | |

Application Serial Number: 16/080489
Filing Date: August 28, 2018
Attorney Docket No.: 78879

ASSIGNMENT

We/I, the undersigned

Lin-Chen Ho, of Taichung, Taiwan; Wei-Wen Tsai, of Taipei, Taiwan; Cheng-Ping Lee, of Miaoli County, Taiwan and Jiun-Fang Wang, of Hsinchu City, Taiwan

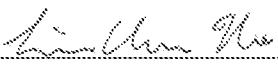
Hereby declare that

We/I are true and first inventor(s) of an invention relating to

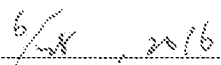
METHOD OF CHEMICAL MECHANICAL POLISHING A SUBSTRATE

which is disclosed in PCT International Application Number PCT/CN16/075071 filed on the 1st day of March, 2016 (Docket No. 78879) which designates States including the United States of America; and, for valuable consideration, the receipt and adequacy of which is hereby acknowledged and in fulfillment of our pre-existing obligation of assignment, we hereby sell, assign and transfer unto Rohm and Haas Electronic Materials CMP Holdings, Inc., a corporation organized and existing under the laws of the State of Delaware in the United States of America and having its mailing address at 451 Bellevue Road, Newark, Delaware, hereinafter referred to as the assignee, the entire right, title, and interest in and to the aforesaid PCT International Application, including any priority rights derived from the aforesaid PCT International Application by virtue of the International Convention for the Protection of Industrial Property for any and all member countries of the aforesaid International Convention, and the entire right, title and interest in and to any and all our inventions, whether joint or sole, disclosed in the aforesaid PCT International Application, and in and to any and all applications for letters Patent for any such inventions in any country whatsoever, and in and to any and all patents for any such inventions in any country whatsoever, with the sole right to file such applications in its name or ours, including the sole right to file such applications under the aforesaid International Convention, together with the sole right to have said patents granted in its name or ours and to enforce said patents and to sue for and recover profits and damages for any and all infringements thereof, and hereby agree, whenever requested, to communicate to us respecting said inventions, to testify in any legal proceeding, to execute all applications, papers, or instruments necessary or required by said assignee, its successors, assigns, and legal representatives to carry into effect any of the provisions of this instrument, and generally to do everything possible to aid said assignee, its successors, assigns and legal representatives to obtain and enforce proper patent protection for said inventions in any and all countries.

IN WITNESS WHEREOF, We have hereunto signed our names on the day and year set forth below.



Lin-Chen Ho



DATE

Wei-Wen Tsai
Wei-Wen Tsai

6/28/2016
DATE

Cheng-Ping Lee
Cheng-Ping Lee

6/28/2016
DATE

Jiun-Fang Wang
Jiun-Fang Wang

6/28/2016
DATE